

ABSTRACT

Methods and systems for managing contaminants are described. One exemplary method ejects fluid from multiple ejection chambers of a printing device in a pattern designed primarily to create fluid flow to move a contaminant present in fluid contained in a fluid-feed channel configured to supply fluid to the multiple ejection chambers. Responsive to the ejection, the method moves fluid in the fluid-feed channel sufficiently to move a contaminant in a desired direction within the fluid-feed channel.